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# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 2

of 2

Application Number 10/823,849  
Filing Date APRIL 13, 2004  
First Named Inventor YEUK-FAI MOK, ET AL.  
Group Art Unit ~~2812~~ 2818  
Examiner Name UNKNOWN David Vu  
Attorney Docket Number AMAT/8298/CMP/ECP/RKK  
Submission Date 7/30/04

## NON PATENT LITERATURE DOCUMENTS

| Examiner Initials* | Cite No.¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published | T² |
|--------------------|-----------|--|----|
| DV                 | C1        | COLOMBO, "Wafer Back Surface Film Removal", Central R&D, SGS-Thomson Microelectronics, Agrate, Italy, Spin Tech Technology, 6 pages, unknown date  |    |
|                    | C2        | HOLM, Electric Contacts Theory and Application, Fourth Completely Rewritten Edition, Springer-Verlag, New York Inc., August 21, 1967, 27 pages.  |    |
|                    | C3        | JIANG, et al., "Variations in Cu CMP Removal Rate Due to Cu Film Self-Annealing", Advanced Metallization Conference in 1998 (AMC 1998), 8 pages.   |    |
|                    | C4        | PITNEY, "NEY Contact Manual", Electric Contacts for Low Energy Uses, 1973.   |    |
|                    | C5        | SIMPSON, et al., "The Electrical Integrity of Copper Plated Wafers Using a Novel Plating Bath Chemistry" Slides Publicly Disclosed, 13 Pages October 17-22, 1999.  |    |
|                    | C6        | SINGER, "Tantalum, Copper and Damascene: The Future of Interconnects," Semiconductor International, June 1998, Pages cover, pages 91-94, 96, & 98.   |    |
|                    | C7        | SINGER, "Wafer Processing", Semiconductor International, June, 1998, page 70.  |    |
|                    | C8        | Laurel Technologies Corporation from <a href="http://www.laurell.com">www.laurell.com</a> , "Two control configurations available- seeWS 400 OR WS-400Lite." 1998, 6 pages.  |    |
|                    | C9        | Welcome to Verteq Online Products Overview, from Verteq from <a href="http://www.verteq.com">www.verteq.com</a> , unknown date   |    |
|                    | C10       | "Metallization & Interconnect", Semitool, Inc., 1998, 4 pages  |    |
|                    | C11       | European Search Report from EP 0 110 3525 dated July 10, 2001.   |    |
|                    | C12       | European Search Report for Application 301415.6 dated December 11, 2000.   |    |
| DV                 | C13       | Austrian Patent Office Search report for Application 00010504 ; unknown date   |    |

Examiner

*Shindland*

Date Considered 10/30/05

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